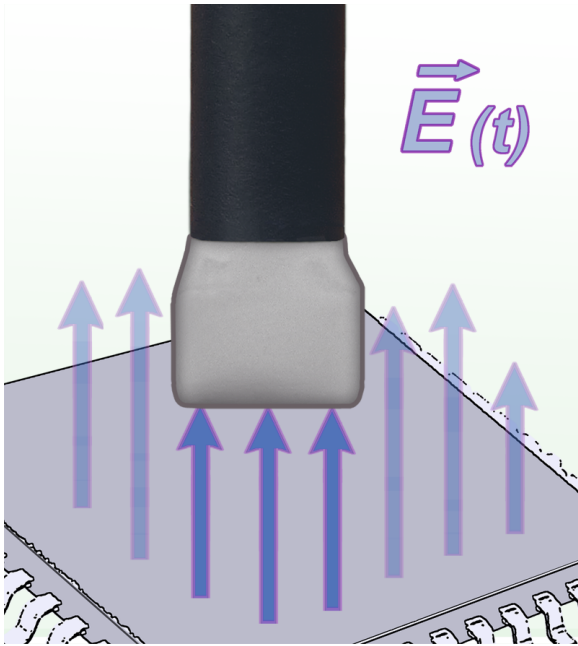


# XF-E 04s

电场探头 (30MHz-6GHz)



## Short description

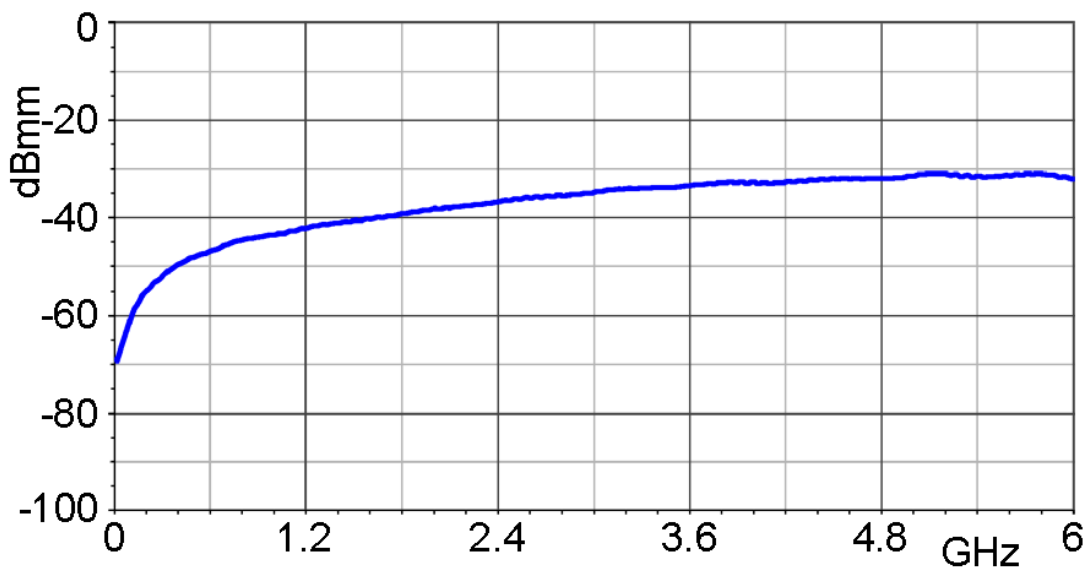
这种近场探头可以检测受测对象 (IC) 耦合产生的电场。探头的侧面采用屏障设计，所以侧面作用的电场不影响测量结果。这种近场探头的灵敏度允许在0.5到10mm的距离检测集成电路及其他电子模块的电场。

The XF-E 04s is a passive near-field probe. In principle it has the same structure as the XF-E 09s probes. To measure, the E-field probe is positioned above or onto components and printed circuit boards. It has a current attenuating sheath and, therefore, its upper half is electrically shielded. It can be connected to a spectrum analyzer or an oscilloscope with a 50  $\Omega$  input. The E-field probe has an internal terminating resistance.

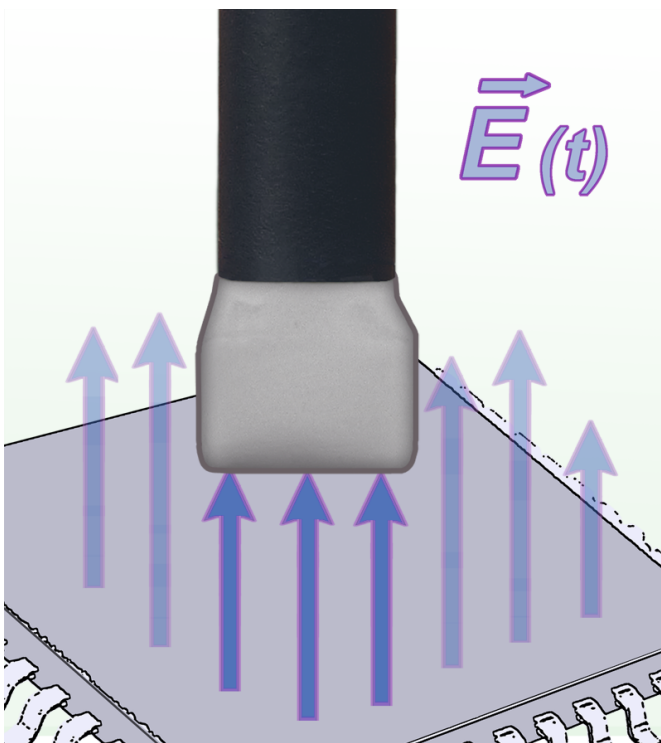
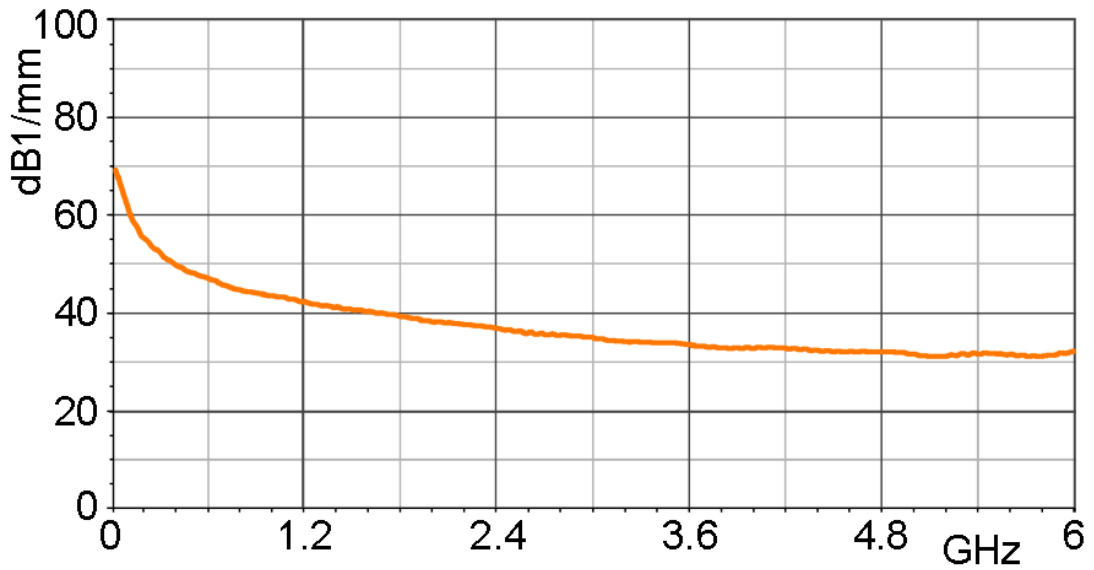
## Technical parameters

|      |                           |
|------|---------------------------|
| 频率范围 | 30 MHz ... 6 GHz          |
| 探头尺寸 | $\approx (5 \times 5)$ mm |
| 输出接口 | SMA, female, jack         |

频率特性 [dB $\mu$ V] / [dB $\mu$ V/mm]



电场校正曲线 [dB $\mu$ V/mm] / [dB $\mu$ V]



# XF-E 04s

电场探头 (30MHz-6GHz)

Probe head

